

Quantum Cascade Laser (QCL) epi wafer specification

Specifications

Dimensions: Available in 2 inch wafers Materials: InP-based heterostructures (e.g.,

 $In_xGa_{1-x}As$ and $In_xAl_{1-x}As$)

Epitaxial Structure: Repeated active-injector stages, lattice-matched or strain-compensated to InP

Wavelength Range: 4 to 12 µm (customizable

upon request)

Uniformity: < ±5% across 2-inch wafer **Growth Method**: MOCVD (Metal-Organic

Chemical Vapor Deposition)

Applications: Industrial, medical, military, and

research sectors

Features and Performance

Thickness Accuracy: < 5% error, validated by XRD and TEM

Interface Quality: Superlattice structures with

RMS roughness < 0.5 nm

Strain-Balanced Design: In composition in $In_xGa_{1-x}As/In_xAl_{1-x}As$ adjustable from 30–70% to meet customer requirements

Wavelength Control: Emission range tunable from 4 to 13 µm; Room temperature pulsed-wave operation with ridge waveguide structure is guerrrenteed.

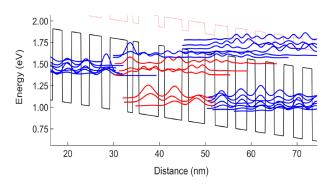
Customizability: All designs can be tailored based on specific application needs

Manufacturing and Quality

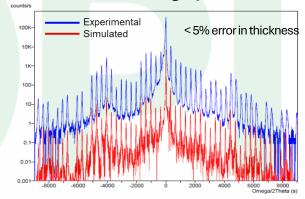
Reliable Production: EPI Solution[™] provides high-performance QCL wafers with consistent quality. Our precise process control ensures reproducibility, high yields, and rapid feedback, supporting a stable supply chain and dependable quality—crucial for device development and scaling.

Manufacturing Excellence: Our QCL wafers are grown via advanced MOCVD systems optimized for material quality. Proprietary growth methods and strict monitoring enable superior uniformity, low defect density, and clean interfaces supporting next-gen applications in sensing, spectroscopy, defense, and healthcare.

Simulation of QCL band diagram



Simulation and Experimental XRD results of the 30 stage QCLs



TEM characterization of the QCLs

